

Novel Sensors for Particle Tracking

5 technologies

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**(part of this is derived from a contribution to the 2021
Snowmass Community Planning exercise)**

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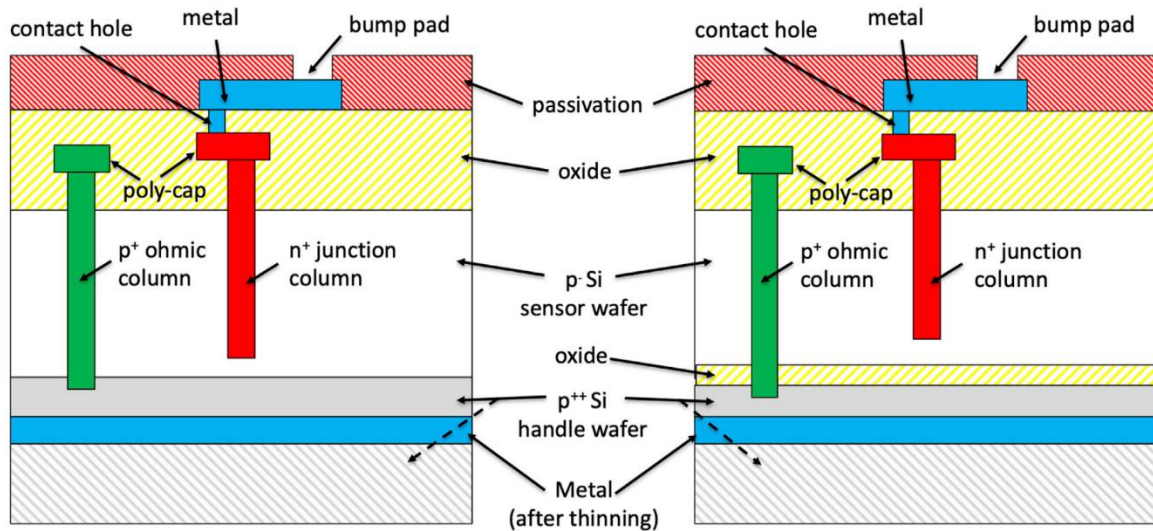
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Novel Sensors for Particle Tracking

3D pixels



3D pixels : introduced by S.Y Parker in 1997

Left from : Progress in 3D Silicon Radiation Detectors , Gian-Franco Dalla Betta and Marco Povoli, Frontiers in Physics, June 2022 | Volume 10 | Article 927690

Left bottom from: «Novel 3D Pixel Sensors for the Upgrade of the ATLAS Inner Tracker », Stefano Terzo, Maurizio Boscardin et al., Frontier In Physics, April 2021, Volume 9 , Article 624668 (Silicon 3D)

The concept can be generalized to other material systems
3D silicon pixels are optimized for radiation hardness with silicon process compatibility

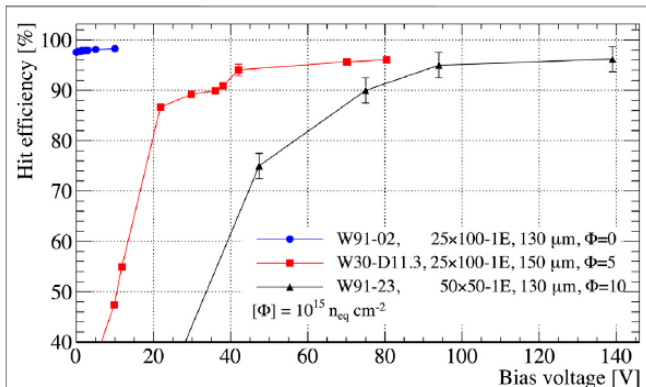


FIGURE 10 | Hit efficiency as a function of the bias voltage for RD53A modules with FBK 3D sensors from second and third batches before and after irradiation. The modules are tuned to a mean threshold of 1 ke.

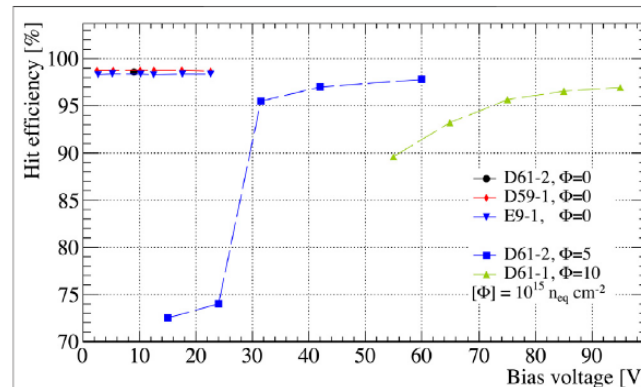


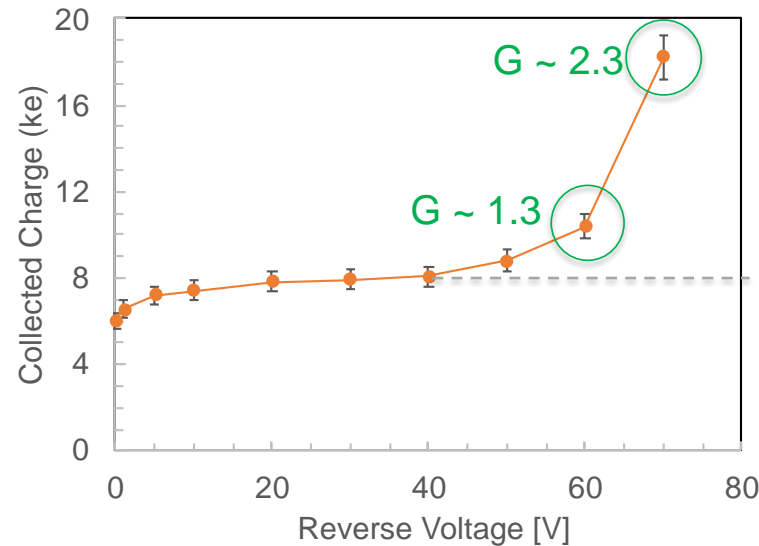
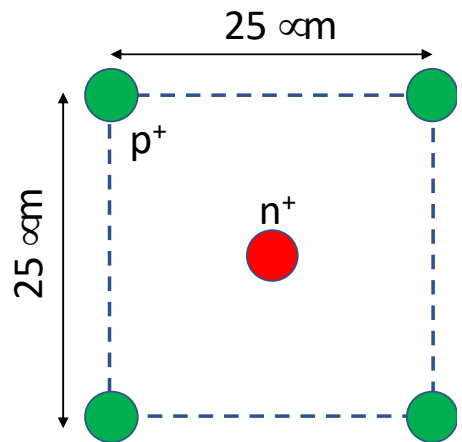
FIGURE 11 | Hit efficiency as a function of the bias voltage for RD53A modules with SINTEF 3D sensors from run four before and after irradiation. The sensors have a 50×50 -1E pixel geometry. For better visibility the data of D61-2 before irradiation (black circles) is shifted by -1 V.

- L_c = distance between the electrodes
- L_d is the mean drift length for carriers before trapping
- $1/L_d = 1/L_{d0} + K\Phi$, with Φ the incident particle integrated flux. The degradation parameter K empirically depends on the material, the nature of the particles and other conditions, it reflects the defect introduction rate.
- K is different from holes to electrons. $N_t = K' F$, where N_t is the trap concentration.
- In this case L_c is much lower than the thickness of the pixels, so we have a number of generated carriers equal to: $N_c \sim \text{Thickness}$, we can set L_c so that $L_c < L_d$
- Improving CCE charge collection efficiency by acting on the aspect ratio which is not possible using a planar configuration $L_c/\text{Thickness}$

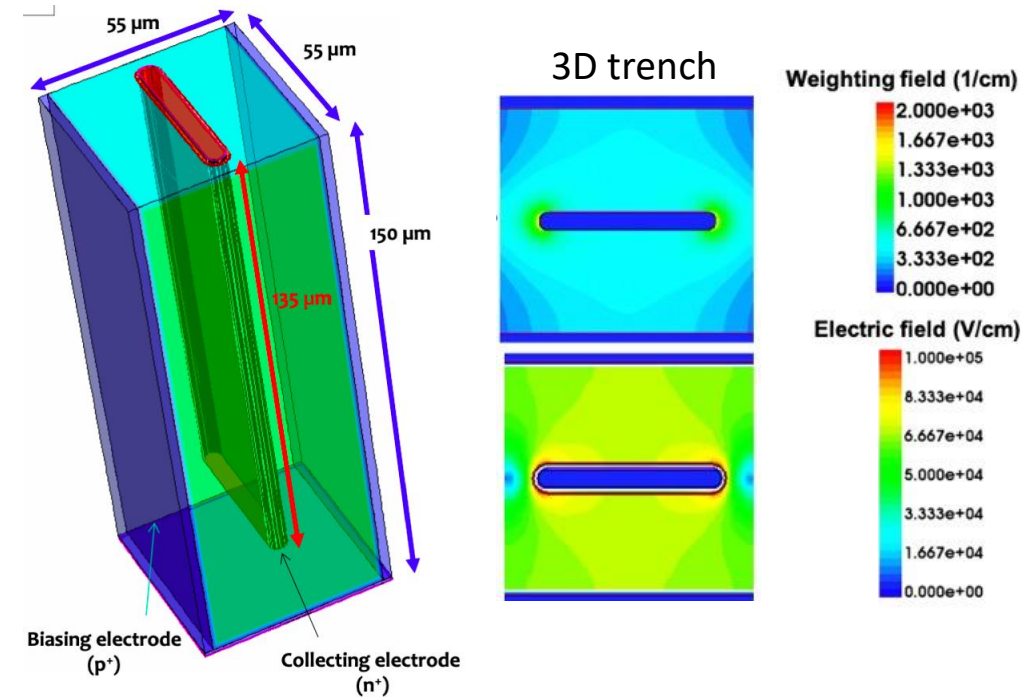
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3D silicon sensors (credit G.F. Dalla Betta)

- 3D sensors are the most radiation-hard silicon detectors
- First installed in the ATLAS IBL, they will equip the innermost tracking layers of ATLAS and CMS detectors at HL-LHC
- They are efficient up to very large irradiation fluences at low voltage (hence low power dissipation)
- For future applications, advanced designs should be optimized



- Very small-pitch 3D sensors can effectively counteract charge trapping and yield moderate charge multiplication at relatively low voltage even before irradiation



- 3D sensors with trenched electrodes offer uniform electric and weighting field distributions for enhanced timing performance (~ 11 ps time resolution recently proved in samples irradiated at $2.5 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}^2$)

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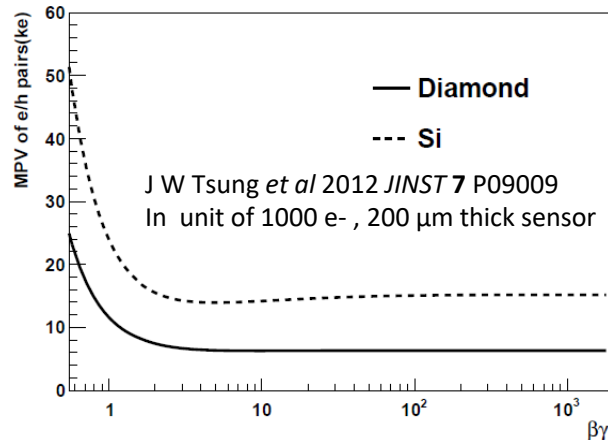
3D diamond pixels

Diamond detectors : within the framework of RD 42 (CERN) since 1994

- 3D diamond pixels is the evolution
- Electrodes fabricated by graphisation using femtosecond lasers
- Conductive electrodes are obtained
- Optimized for Radiation Hardness , with improved time resolution

See, Lucio Anderlini et al., Fabrication and Characterisation of 3D Diamond Pixel Detectors With Timing Capabilities, Frontiers in Physics, November 2020 | Volume 8 | Article 589844

Figures and tables: derived from : J W Tsung *et al* 2012 *JINST* 7 P09009



$$\frac{CCD}{d} = \frac{Q_{\text{collected}}}{Q_{\text{ionized}}} = \frac{\lambda_{e/h}}{d} \cdot \left[1 - \frac{\lambda_{e/h}}{d} \left(1 - e^{-\frac{d}{\lambda_{e/h}}} \right) \right] + (e \leftrightarrow h).$$

Charge Collection Distance,
d : thickness of the detector

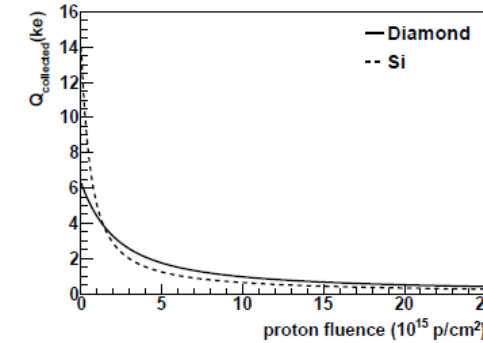
More generally the free drift length is defined by :

$1/\lambda = \sum N_t \sigma_t$ where σ_t is the capture cross section of the trap and N_t is its concentration

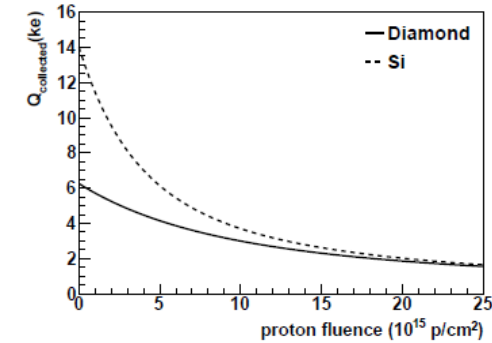
$$\lambda_{e/h} = v_e \tau_e + v_h \tau_h,$$

	25 MeV protons	24 GeV protons
k_{diamond}	$3.02^{+0.42}_{-0.36}$	$0.69^{+0.14}_{-0.17}$
k_{Si}	$10.89^{+1.79}_{-1.79}$	$1.60^{+0.38}_{-0.38}$

J W Tsung *et al* 2012 *JINST* 7 P09009



(a) 25 MeV proton irradiation.



(b) 24 GeV proton irradiation.

- | | | |
|-----------------------------|---|------------------------------------|
| • Parameter : | Si | Diamond |
| • δ : | 0.95 eV | 1.84 eV |
| • I | 174 eV | 81 eV |
| • w_i : | 3.61 eV | 13.1 eV |
| • E_g | 1.1 eV | 5.5 eV |
| • ni | $1^{+10}_{-3} \text{ cm}^{-3}$ | $1^{+27}_{-3} \text{ cm}^{-3}$ |
| • Resistivity (I) | $3.2 \cdot 10^5 \Omega \cdot \text{cm}$ | $> 10^{42} \Omega \cdot \text{cm}$ |
| • Similar effective masses. | | |

Mot of these are extracted from: J W Tsung *et al* 2012 *JINST* 7 P09009
I and d are necessary to calculate the energy deposit in the layer
I = mean excitation energy

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DoTPiX

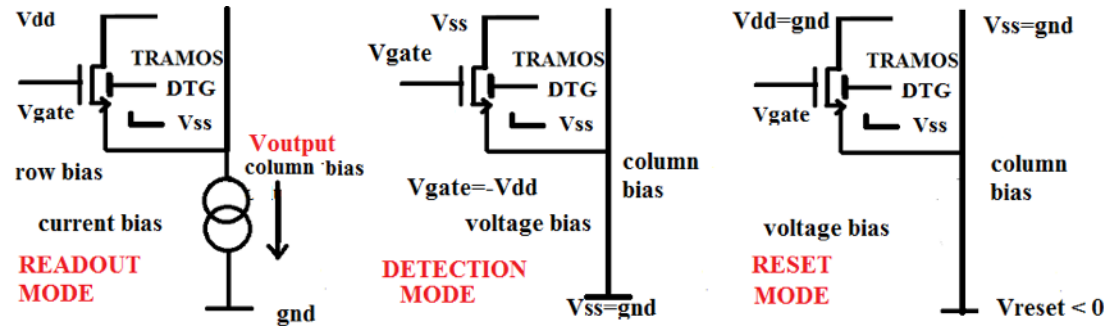


Figure 1: The operational principle of the DoTPiX structure within a pixel array (row and column); the array readout is similar to those of CMOS sensors, with detection, readout, and reset modes. The end of column is connected to a preamplifier, for digital or hit/no hit readout mode. Power dissipation occurs only during readout, due to the biasing scheme. In detection mode, $V_{gate} < V_{drain}$ and V_{source} , to collect holes in the buried gate.

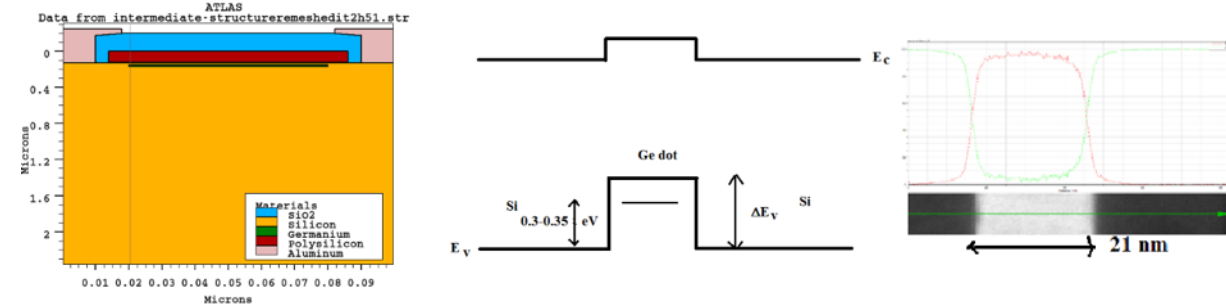
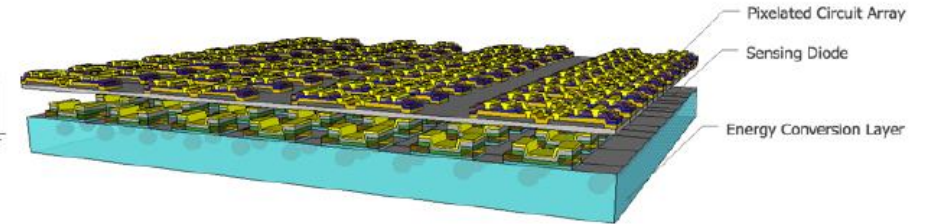
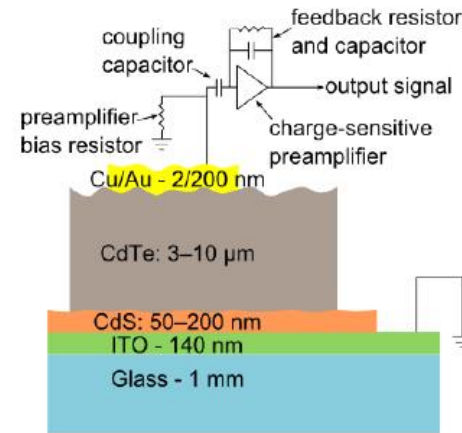
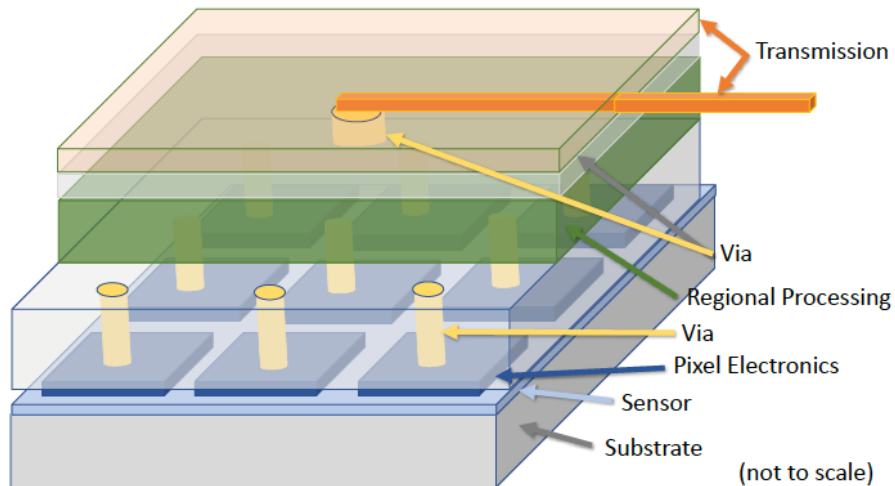


Figure 2: For the DoTPiX project: (left) the TCAD simulation structure; (center) Ge hole quantum well, and (right) results of the processing (on a full wafer), the deposition of a thin Ge layer. This results from electron microscopy, STEM Energy Dispersive X Spectrometry (STEM-EDX). The Ge concentration reaches 95 percent in the 21 nm thick buried layer. The wafer prepared this way should be CMOS compatible with some mitigation of the thermal budget of the process.

- **Proposed in 2017**, derived from another structure (TRAMOS 2010) : goal ultimate point to point spatial resolution ($\sim 1\mu\text{m}$)
- See : N. T. Fourches, “Ultimate Pixel Based on a Single Transistor With Deep Trapping Gate”, IEEE Trans. on Electron Devices 64, pp. 1619-1623 (2017). <https://doi.org-98/10.1109/TED.2017.2670681>.
- Accumulation of holes in the buried Ge layer , modulation of the source-drain current in read mode. No power dissipated in detection mode
- Up to now , simulations (TCAD) have shown the operational capabilities of the device. UHV-CVD growth (C2N) is now under way to obtain a Si/Ge On Silicon structure , and with some CMOS similar processing a testable device. Thermal budget is one of the key parameter.
- GEANT4 simulations have shown that for thin devices one micron squared pixels are close to the optimum.

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Thin Film detectors



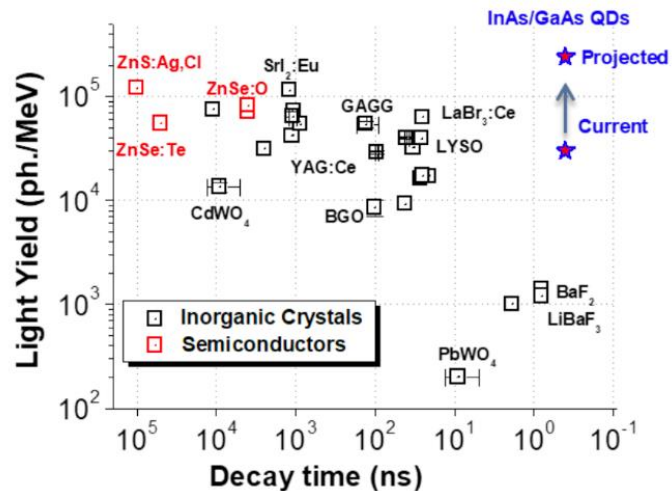
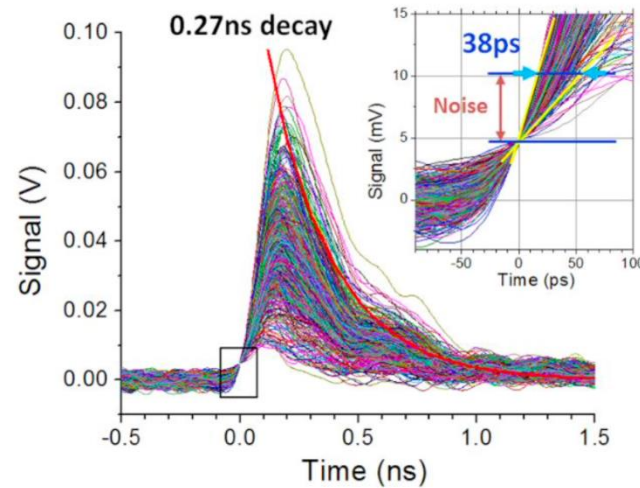
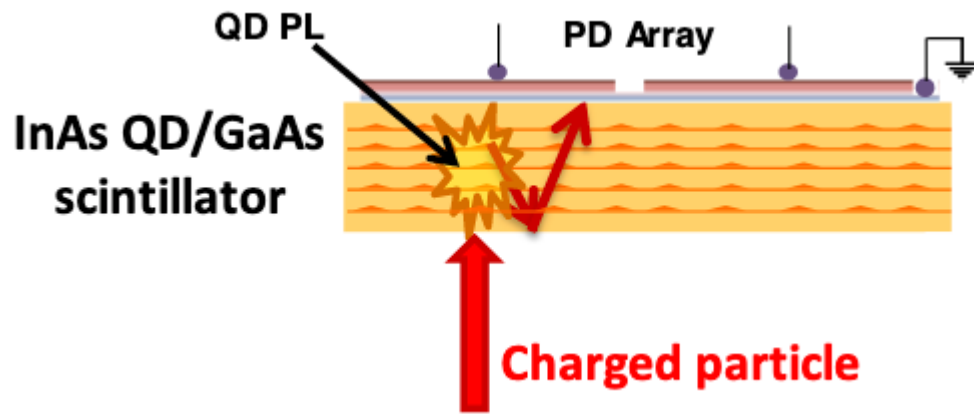
- Optimized for cost effective large area, and material choice
- Flexible substrate is one of the objectives
- Use material deposition techniques and growth with a large choice of materials

From : Potential of Thin Films for use in Charged Particle Tracking Detectors, J. Metcalfe et al.

<https://doi.org/10.48550/arXiv.1411.1794>

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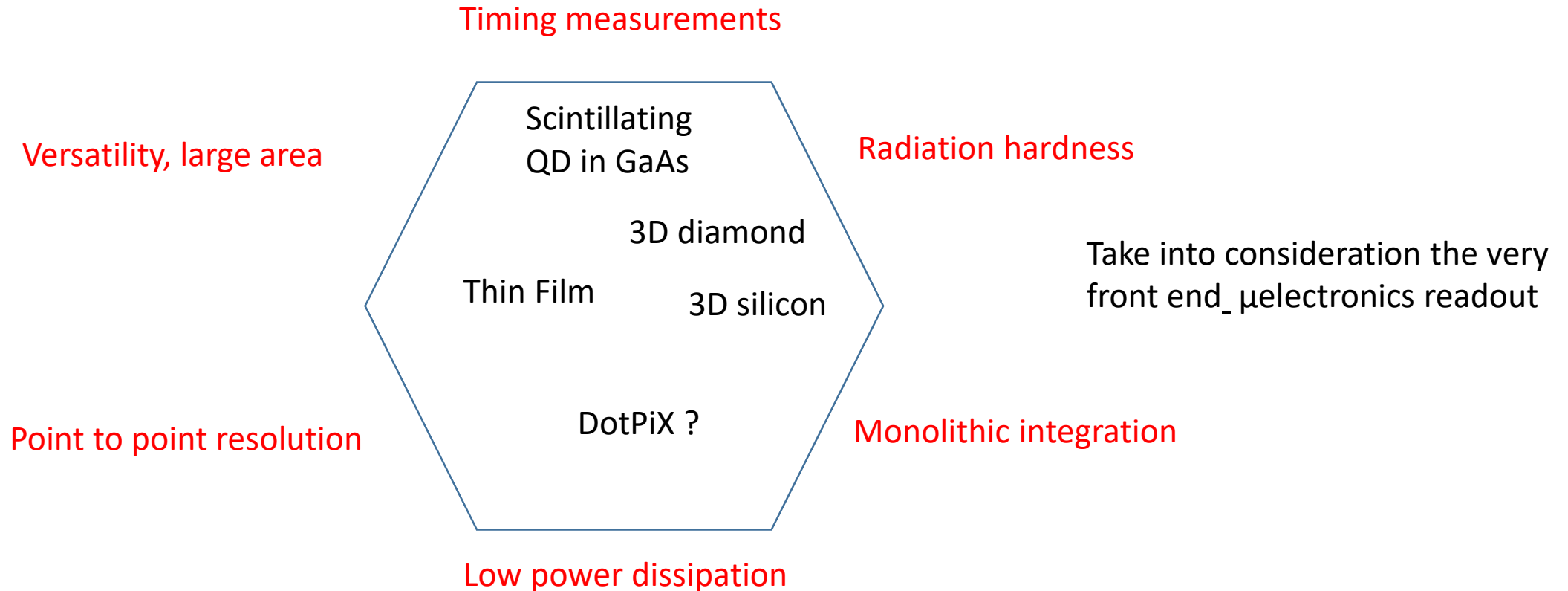
Scintillating Quantum Dots in GaAs for Charged Particle Detection



- Optimized for timing measurements
- High granularity
- Use of GaAs electronic on the same substrate
- See : S. Oktyabrsky et al., Integrated semiconductor quantum dot scintillation detector: Ultimate limit for speed and light yield," IEEE Trans. Nucl. Sci. 63 (2016) 656-663.

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The optimisation diagram ...



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Thank you for your attention